

FIG. 1 (PRIOR ART)

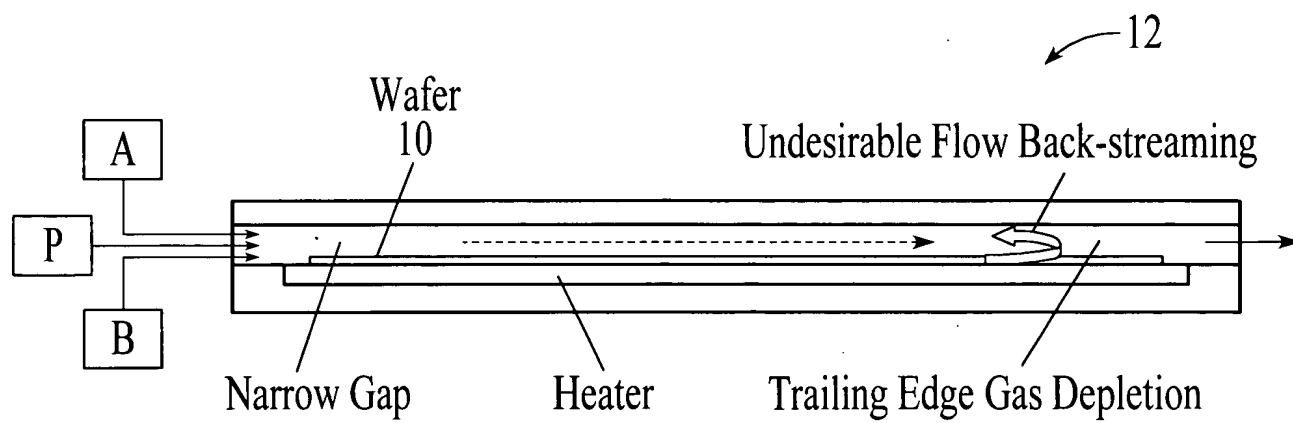


FIG. 2 (PRIOR ART)

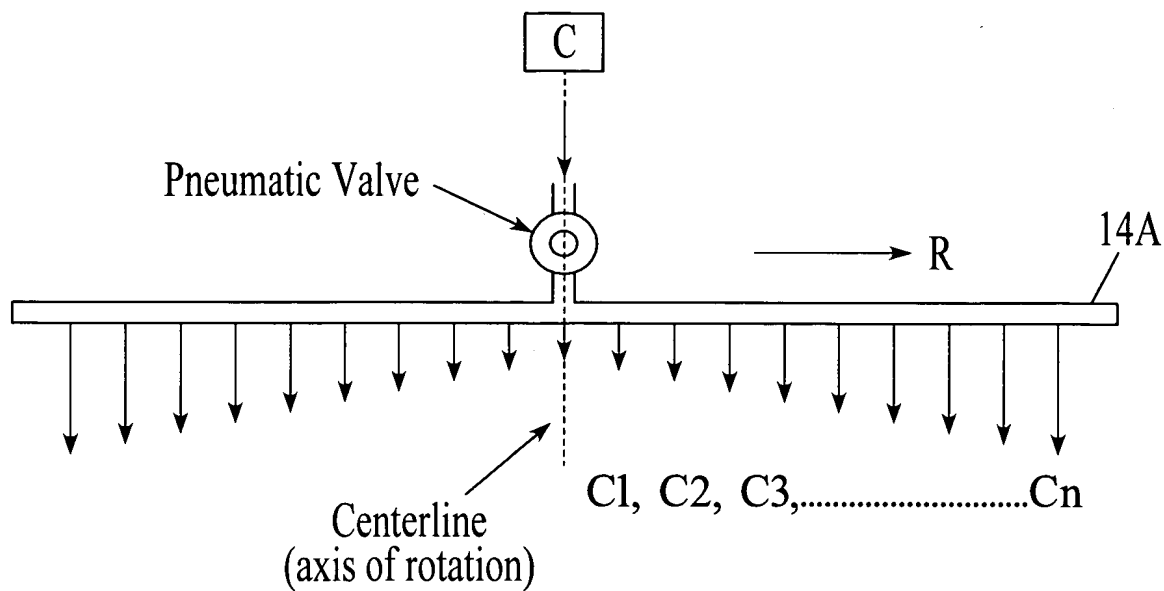


FIG. 3A

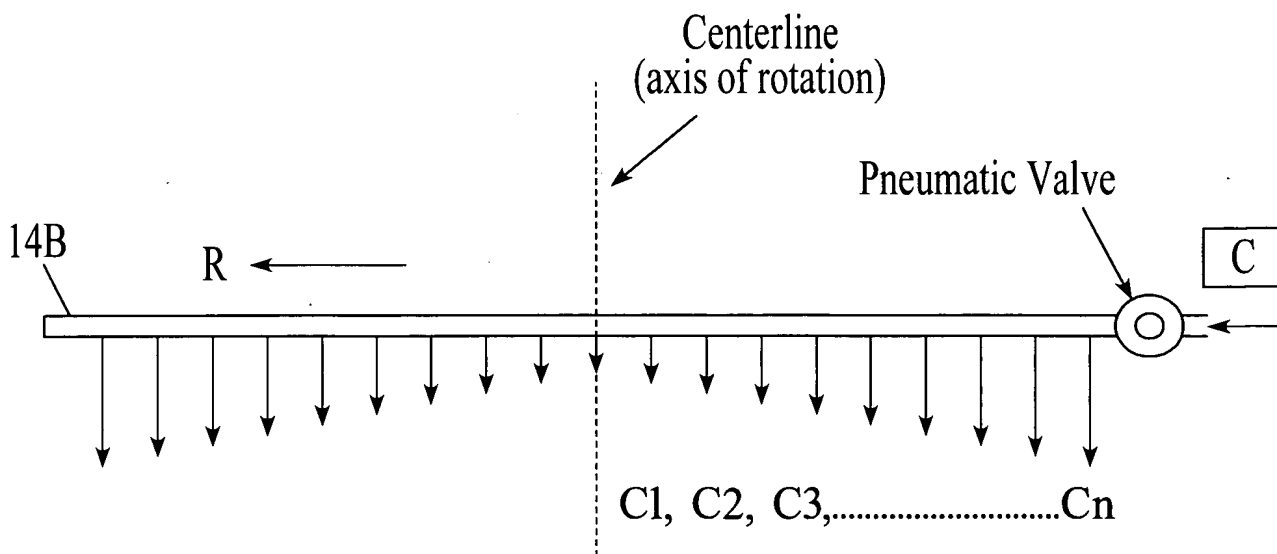


FIG. 3B

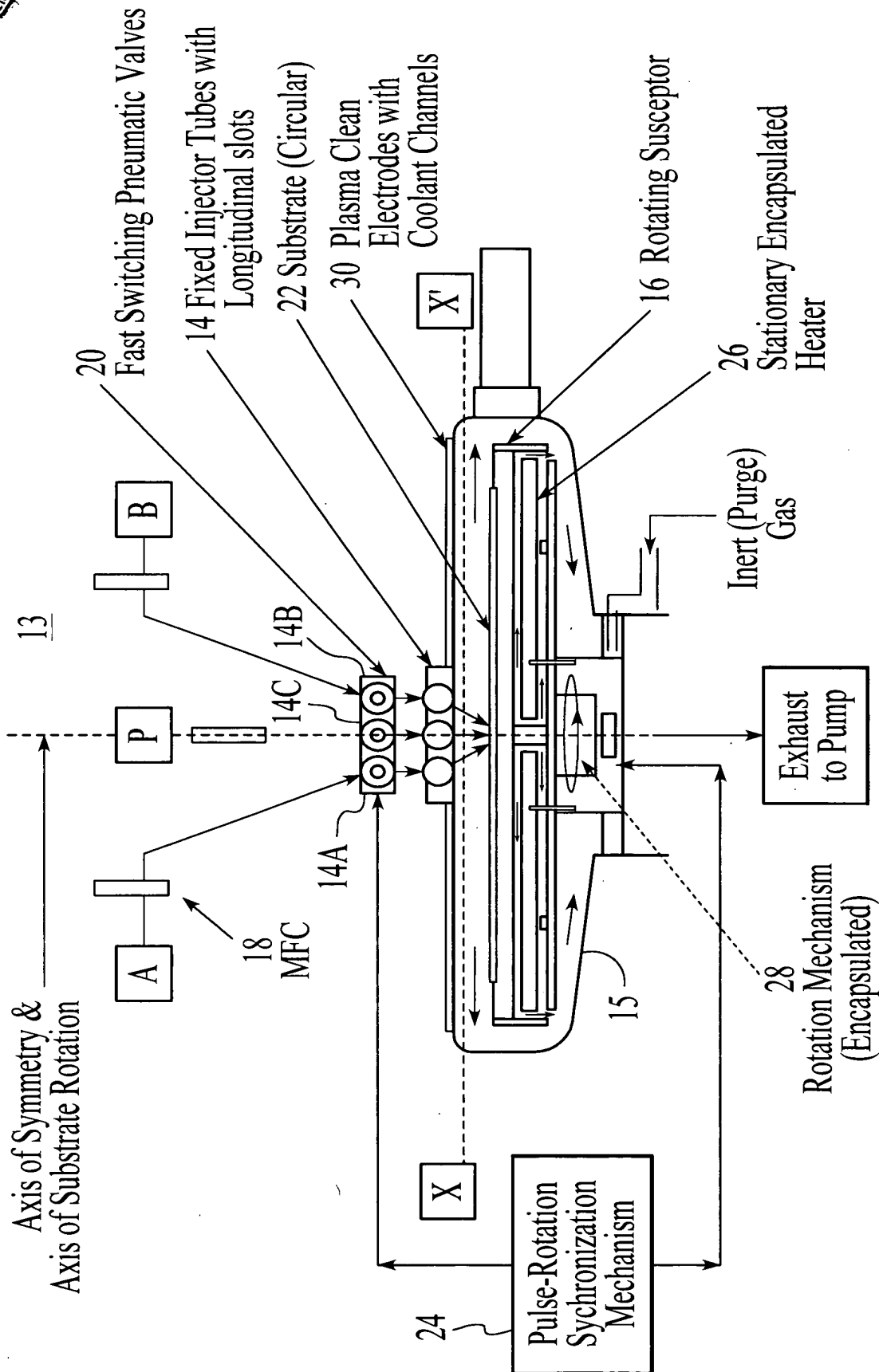
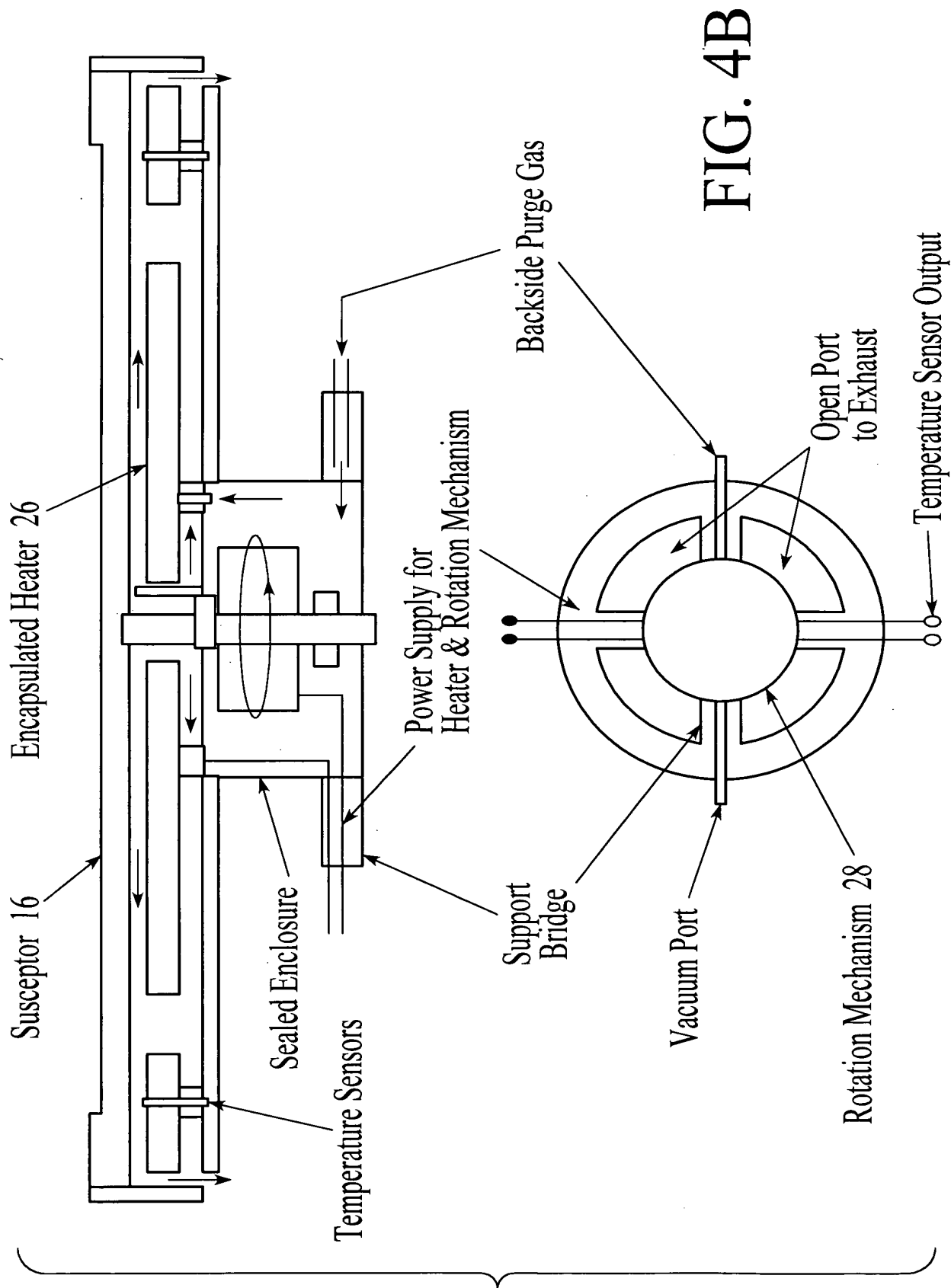


FIG. 4A



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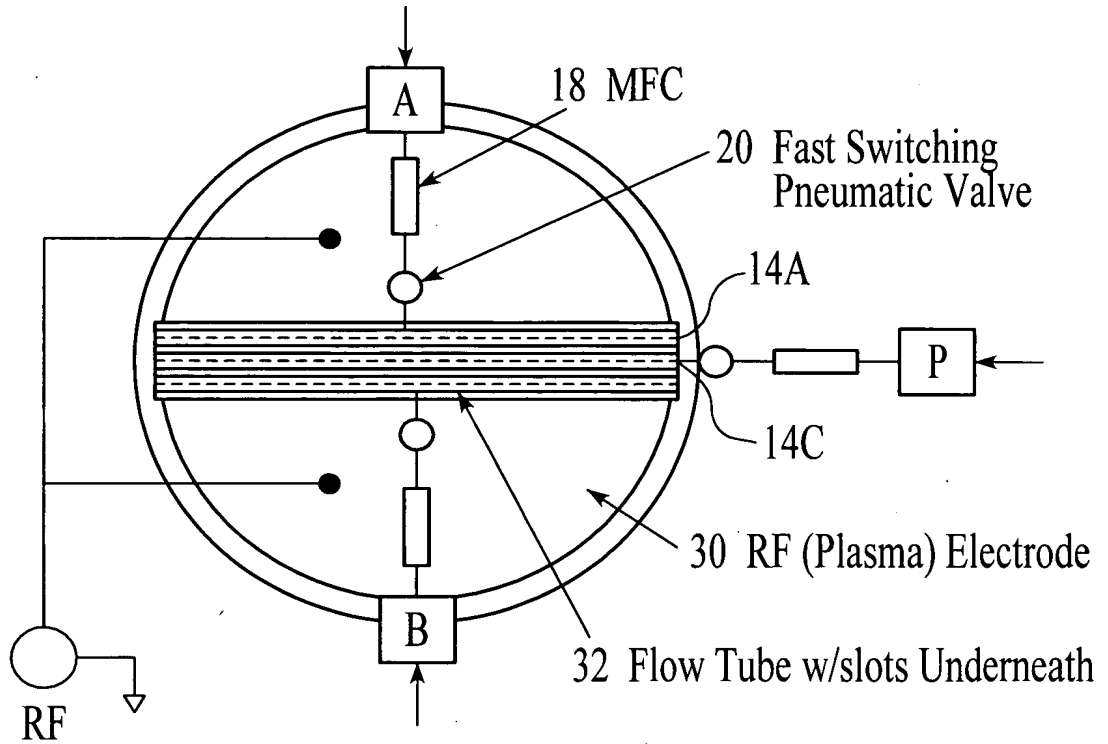


FIG. 5

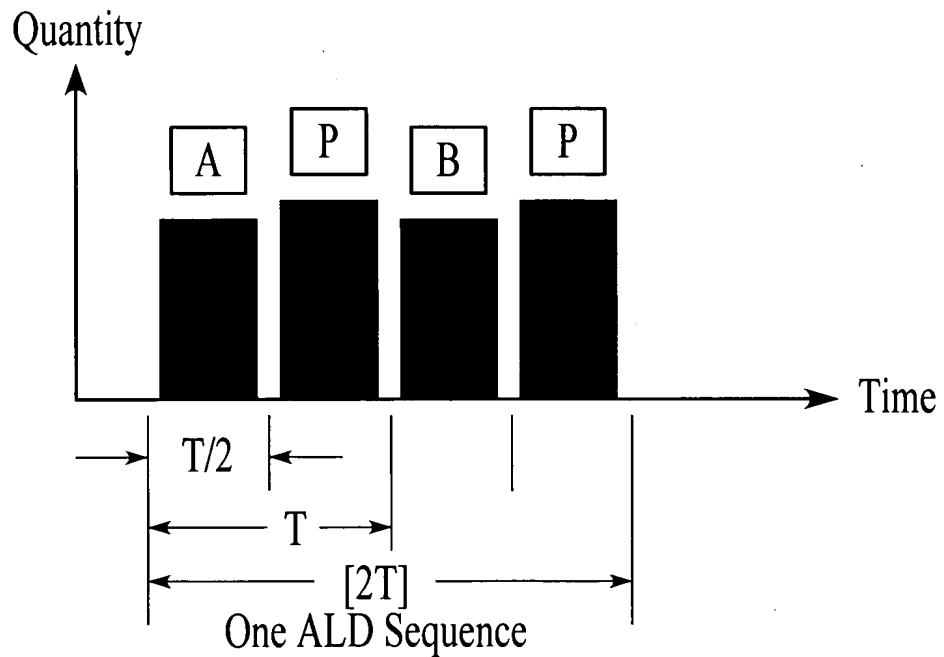


FIG. 6

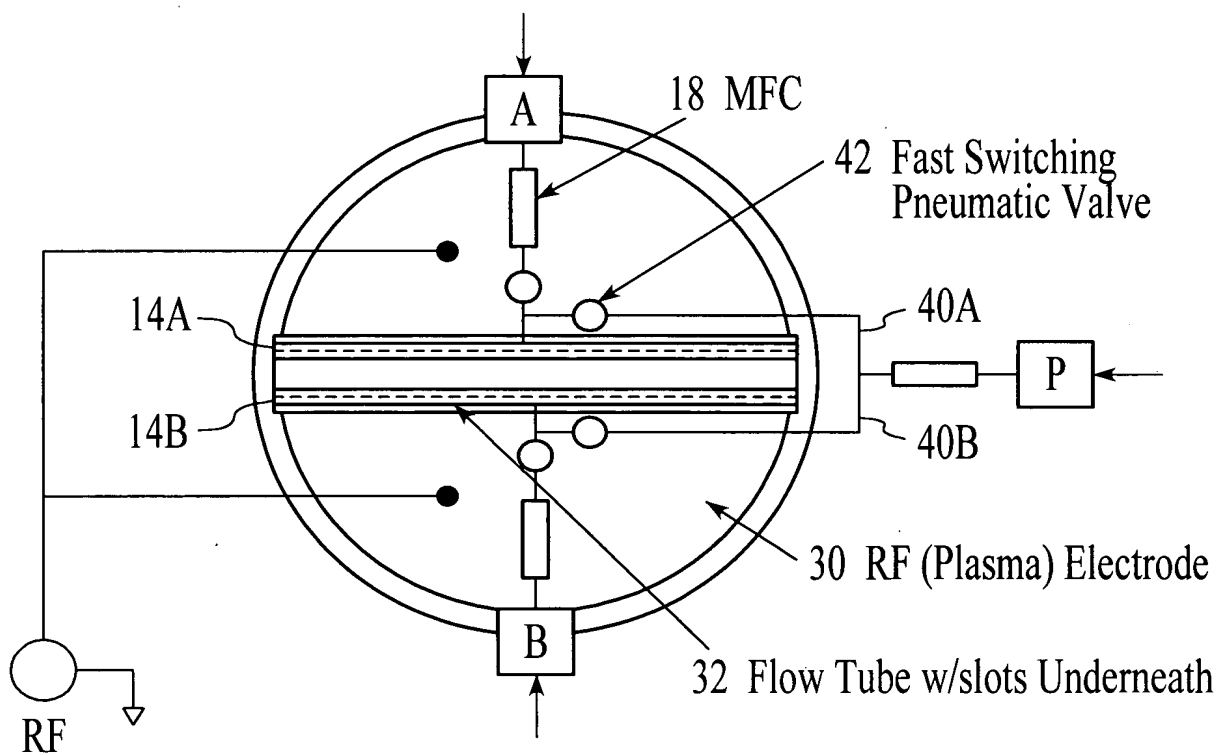


FIG. 7

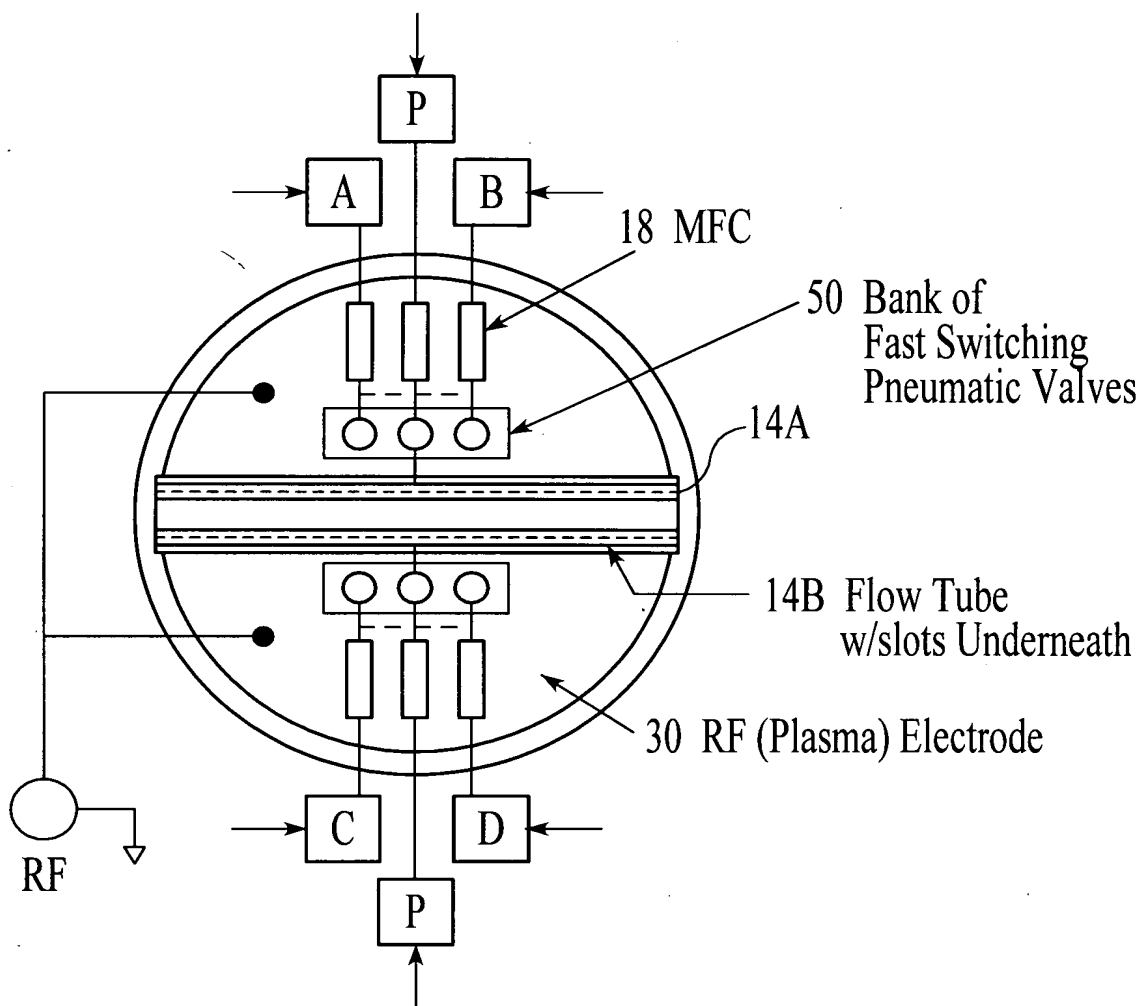


FIG. 8

The diagram illustrates a plasma processing system 10. It features a central chamber 14 with a horizontal flow tube 14A w/slots underneath. The chamber is divided into regions 14B and 14C. Gas inlets A and B enter from the top, and outlets C and D exit from the bottom. A bank of fast switching pneumatic valves 52 is located above and below the chamber. A flow tube w/slots underneath 52 is also shown. The chamber is connected to an RF (Plasma) Electrodes 30, which is connected to an RF source. A pressure gauge P is connected to the chamber via a line 14C.



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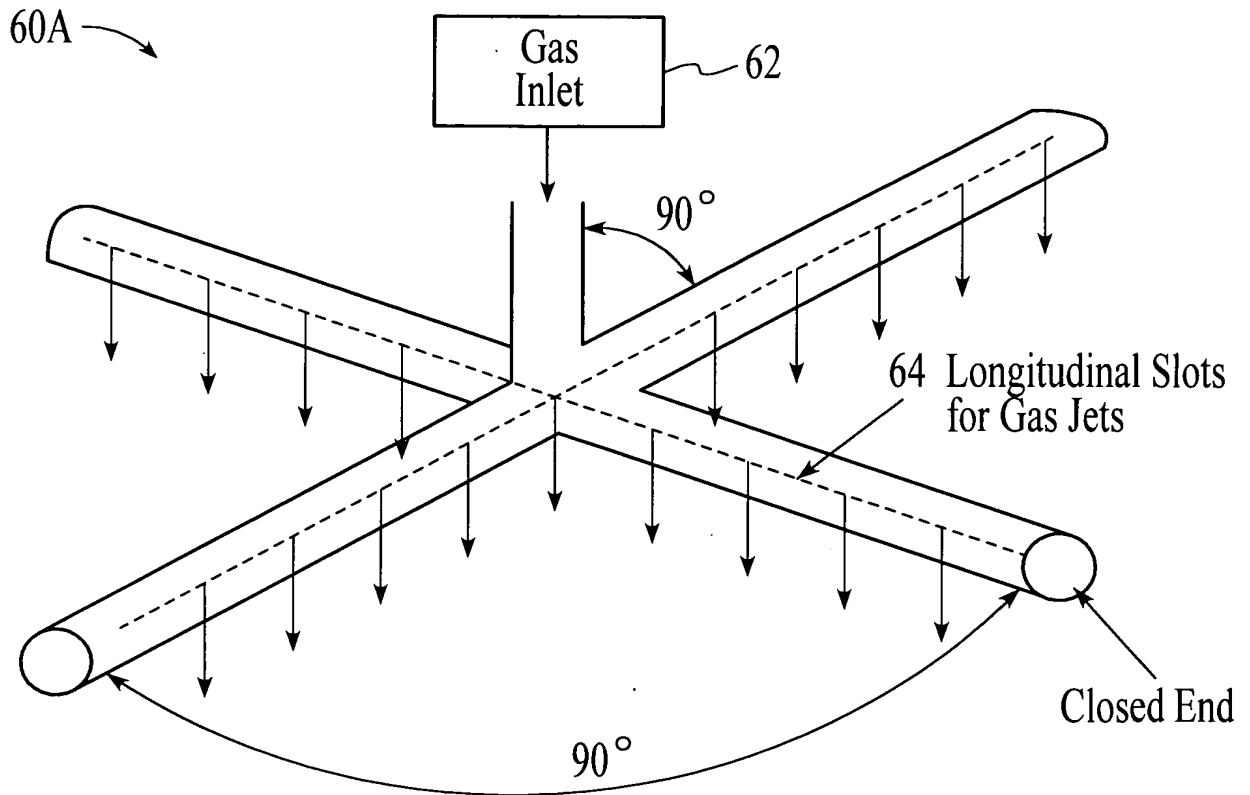


FIG. 10A

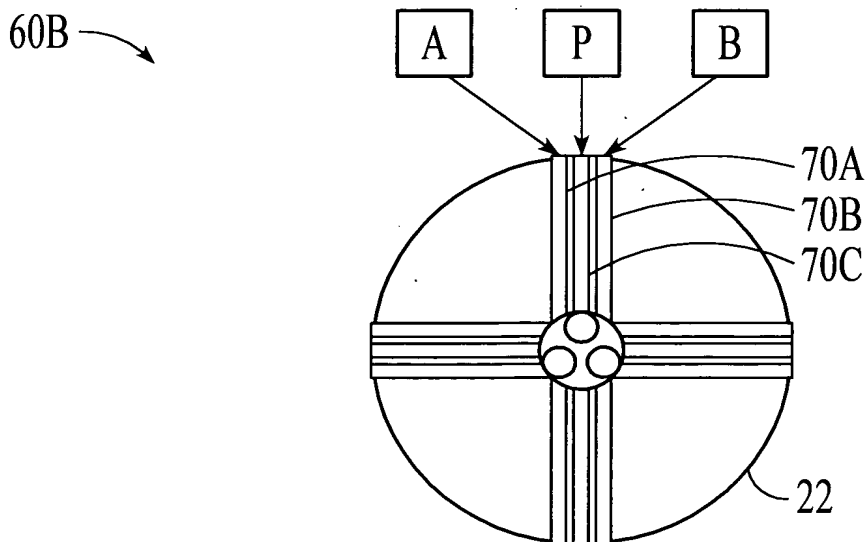


FIG. 10B

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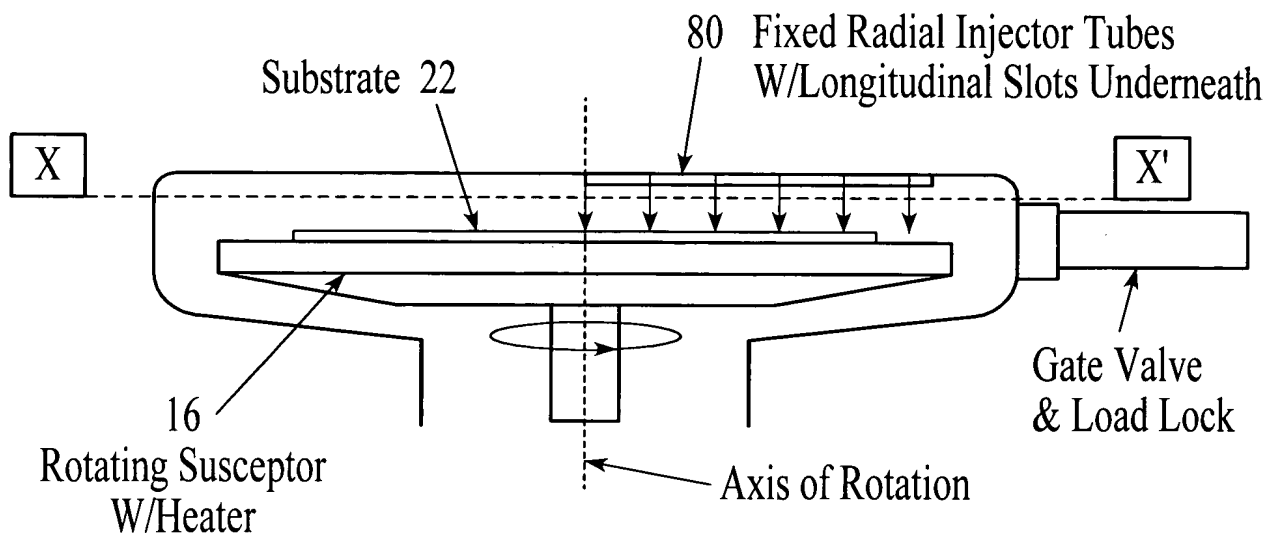


FIG. 11A

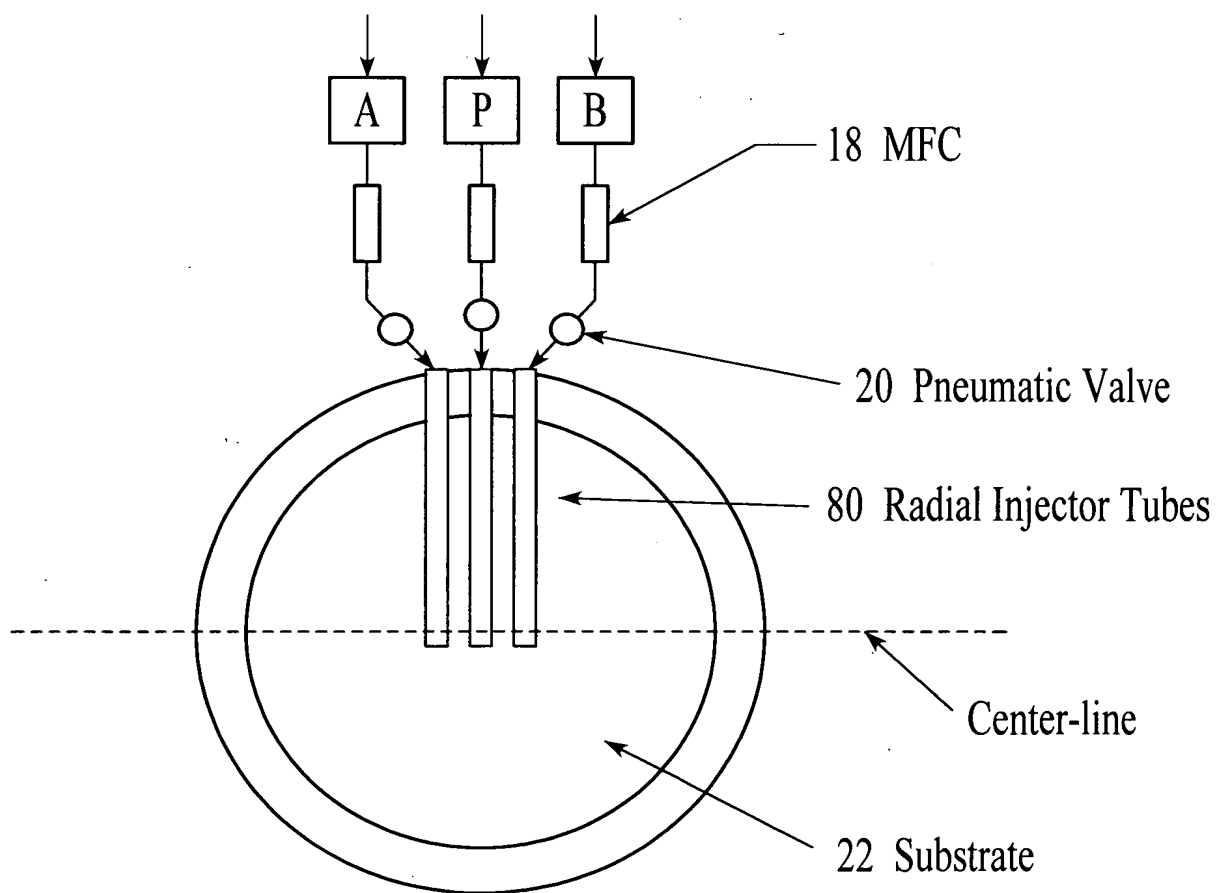


FIG. 11B

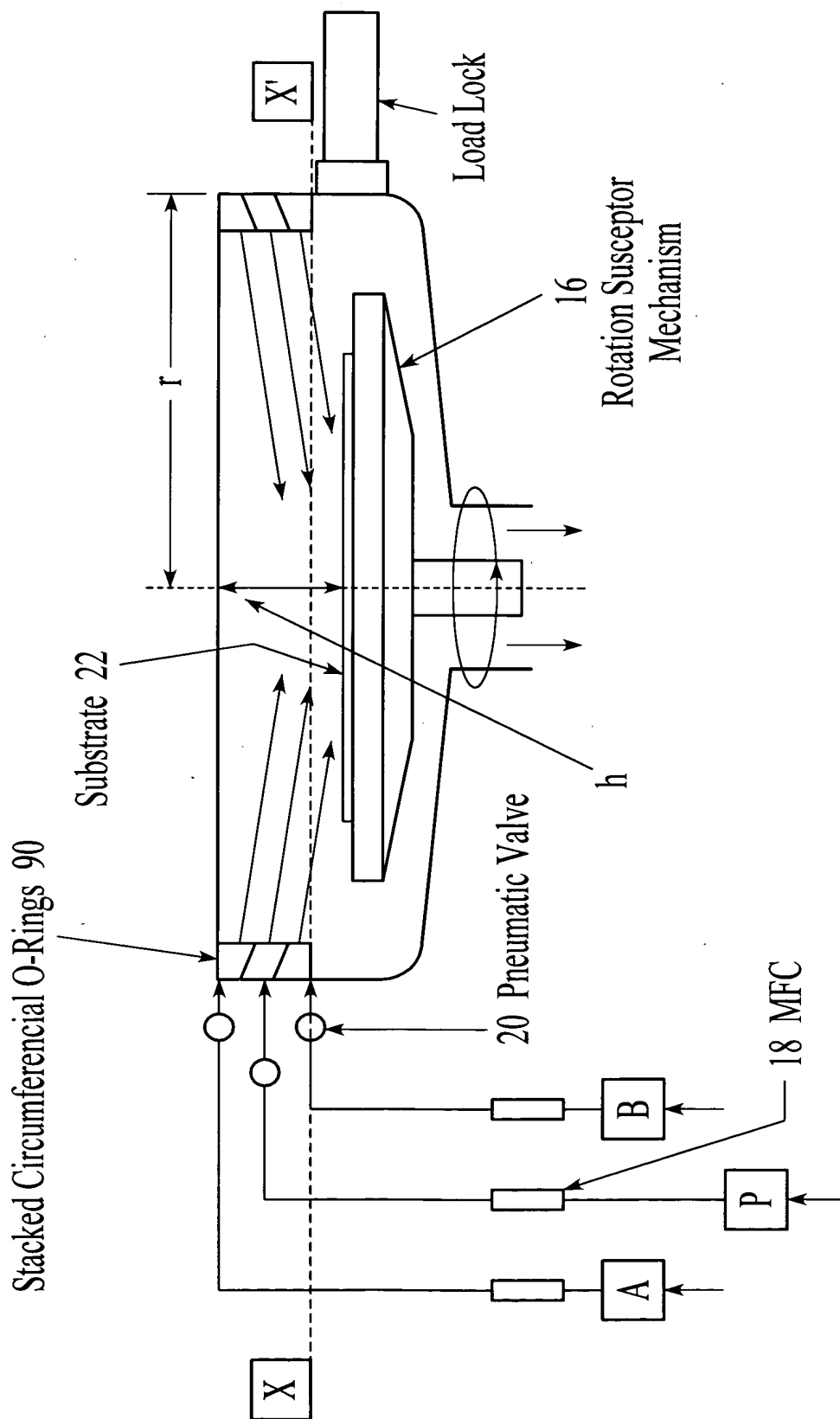


FIG. 12

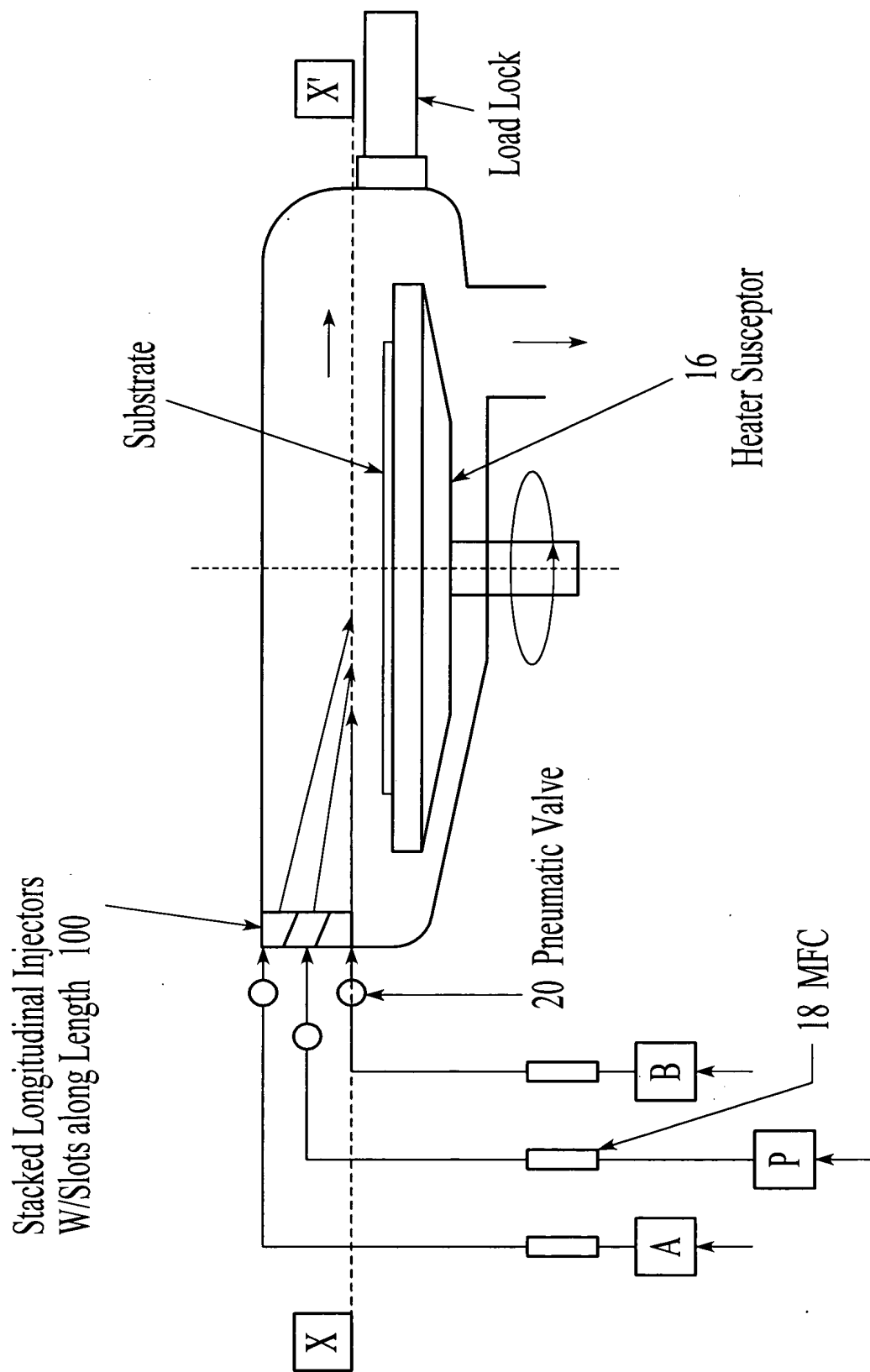


FIG. 13A

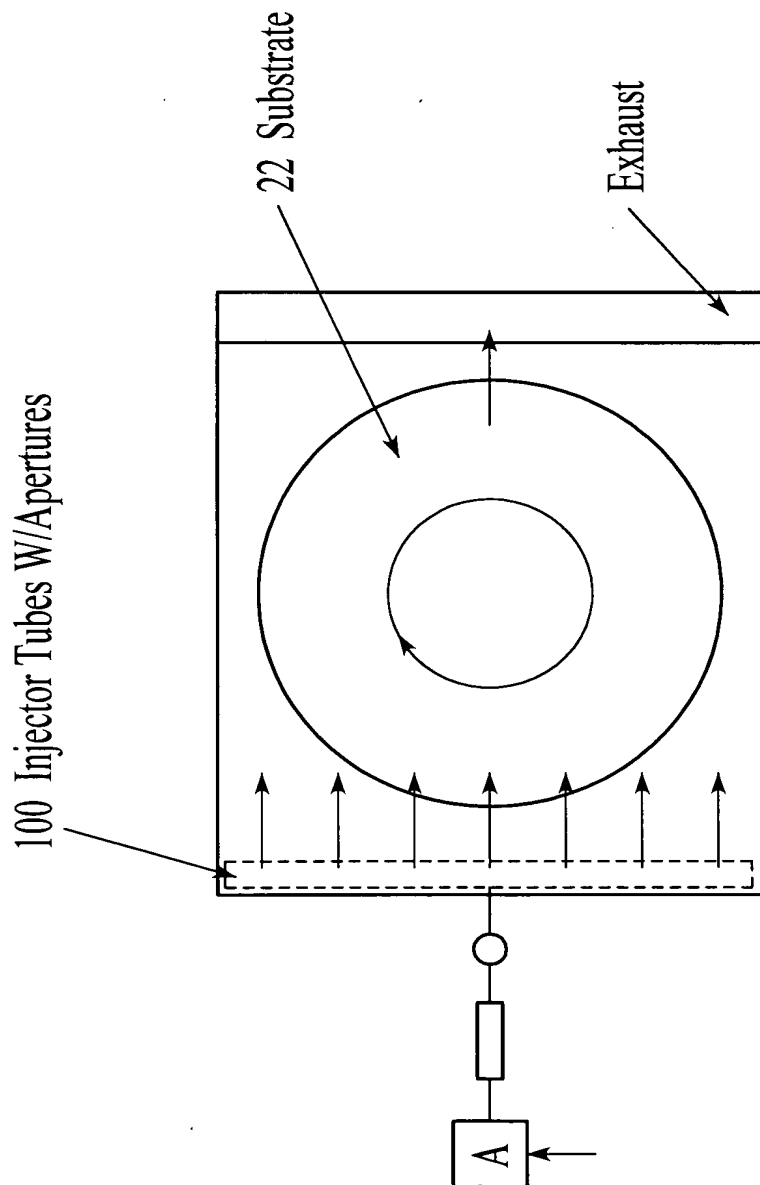
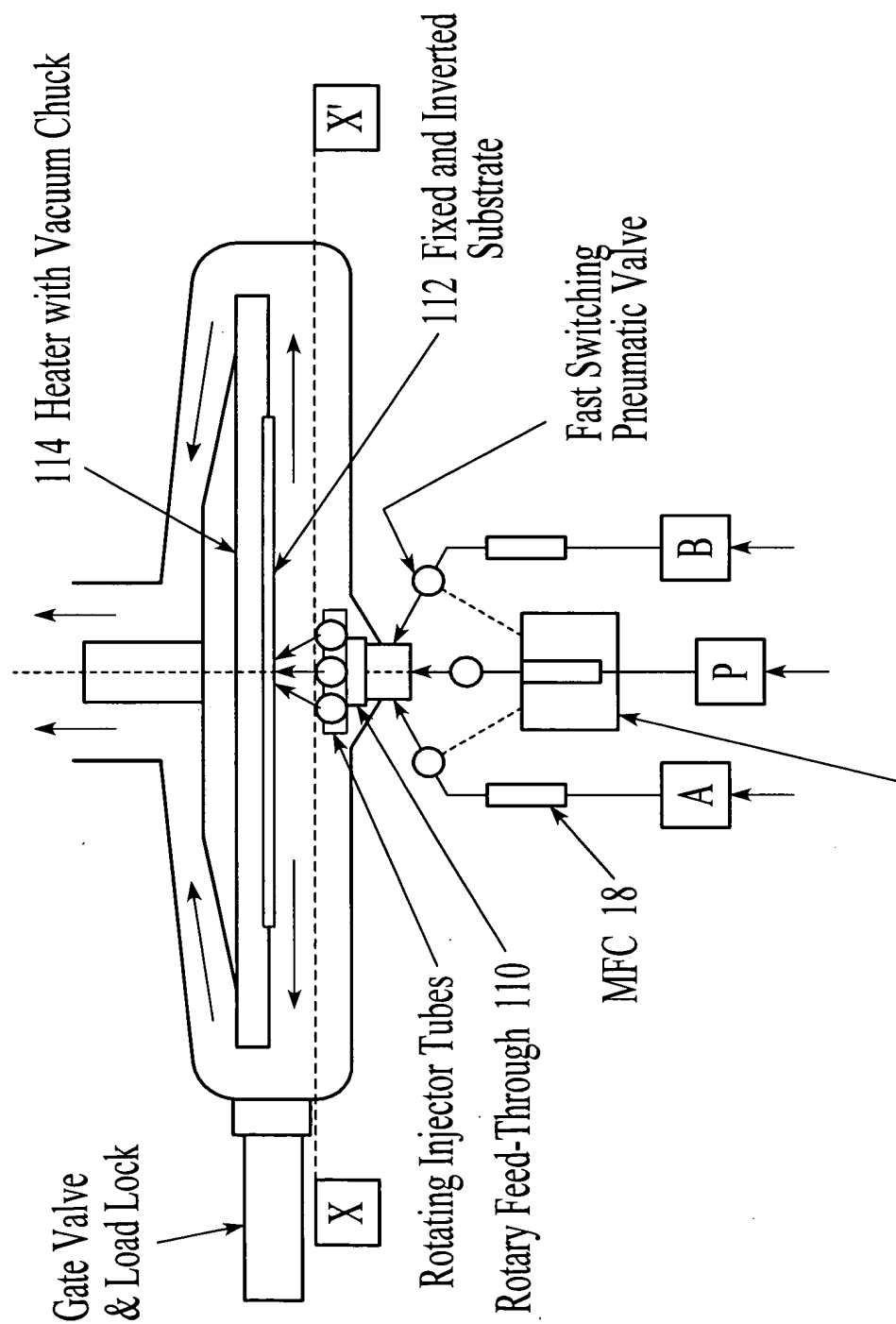


FIG. 13B

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108 Rotation Mechanism  
Coordinated W/Pneumatic valves

FIG. 14